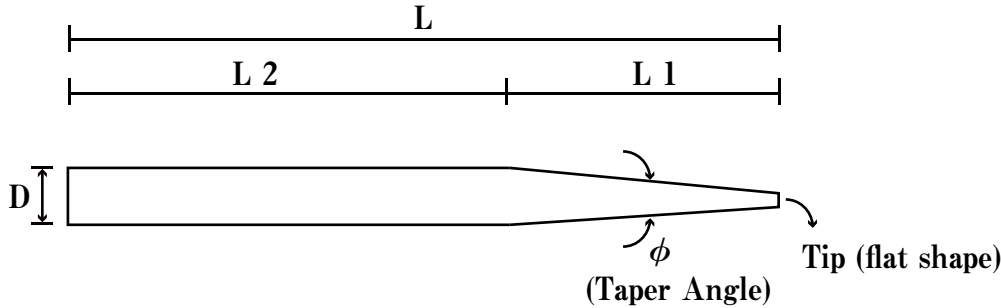


Processing Details of Ultra fine Wire into a Needle shape

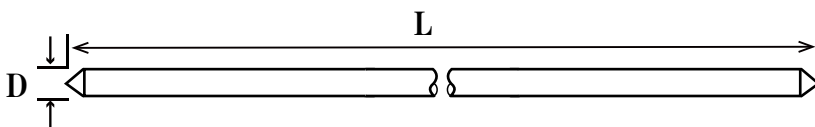
Specs. of Probe Needle for Semiconductor Test

(1) For Cantilever Type & Vertical Contact Probe Card



- **Material**
Ag-Pd-Cu alloy, P7 (Paliney 7),
ReW (Rhenium-Tungsten), W (Tungsten) etc.
Any material can be processed.
- **Tip Diameter**
 $\phi 0.003\text{mm} - 0.012\text{mm}$ (tolerance: ± 0.001 mm)
- **Taper Length (L1)**
Up to 40 times of Wire Diameter (D)
- **Total Length (L)**
30mm - 120mm or so
- **Wire Diameter (D)**
 $\phi 0.05\text{mm} \sim 0.30\text{mm}$

(2) Wire Probe (MEMS type)



- **Material**
Rh (Rhodium), Ag-Pa-Cu alloy, P7 (Paliney 7),
ReW (Rhenium-Tungsten), W (Tungsten) etc.
Any material can be processed.
- **Tip Angle**
 $30^\circ \sim 60^\circ$
- **Wire Diameter (D)**
 $\phi 0.02\text{mm} \sim 0.08\text{mm}$
- **Total Length (L)**
3.5mm ~ 20mm

• Tip Shape

